

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshikazu MIYAJIMA et al.

Application No.: 10/022,506

Filed: December 20, 2001

For: EXPOSURE APPARATUS, DEVICE

MANUFACTURING METHOD.

SEMICONDUCTOR MANUFACTURING) FACTORY, AND EXPOSURE APPARATUS:

MAINTENANCE METHOD

Commissioner for Patents Washington, D.C. 20231

Examiner: Unassigned

Group Art Unit: 2811

April 17, 2002

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 form. Copies of the listed documents are also enclosed.

This Information Disclosure Statement is being filed before the issuance of a first Office Action on the merits. Therefore, no fee under 37 C.F.R. 1.97(c)(2) is believed due. Nevertheless, the Commissioner may charge Deposit Account No. 06-1205, should any fee be due for filing this paper.

Applicants request that the above information be considered by the Examiner and that a copy of the enclosed PTO-1449 form be initialed and returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted.

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